

Enrolment for the module

- Within six weeks after starting the lectures

Requirements for written examination

- Regular participation in lectures and exercises



Written examination

Monday, 22nd February 2016, 10:00 - 12:00 hours,
lecture hall 2, Abbeaum

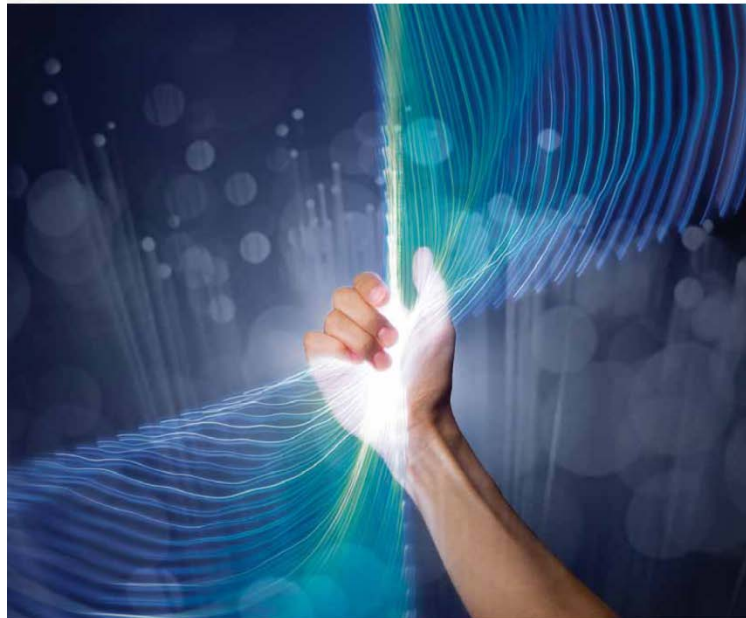


4 credit points

1.1. Contents of the Lectures



AGENDA PHOTONIK



November 2010

GEFÖRDERT VOM





Contents

1. Introduction
2. Interferometry
3. Interferometric Wavefront Analysis
4. Wavefront Sensors
5. Holography and Holographic Interferometry
6. Structured Light Illumination
7. Future Prospects

References



- Bass (Ed.)** *Handbook of Optics II*, McGraw-Hill, New York, 1995
- Born/Wolf** *Principles of Optics*, Pergamon Press, Oxford, 1999
- Gasvik** *Optical Metrology*, Wiley & Sons, Chichester, 1987
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- Hariharan** *Interferometry*, Cambridge Univ. Press, 1986
- Hernandez** *Fabry-Perot-Interferometer*, Cambridge Univ. Press, 1986
- Hecht** *Optics*, Addison Wesley, San Francisco, 2002
- Klein/Furtak** *Optik*, Springer-Verlag, Berlin 1986
- Kreis** *Holographic interferometry*, Akademie Verlag, Berlin, 1996
- Lauterborn** *Kohärente Optik*, Springer-Verlag, Berlin, 1993
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References



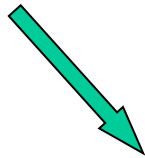
- Malacara u.a.** *Handbook of Optical Engineering*, Dekker, New York, 2001
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- Reynolds u.a.** *Physical Optics Notebook: Tutorials in Fourieroptics*, SPIE, 1989
- Sirohi (Ed.)** *Speckle Metrology*, Dekker, New York, 1993
- SPIE** *Proceedings*
- Steel** *Interferometry*, Cambridge University Press, Cambridge, 1987
- Young** *Optik, Laser, Wellenleiter*, Springer-Verlag, Berlin, 1997
- Wolf (Ed.)** *Progress in Optics*, North-Holland Physics Publishing, Amsterdam, Book series since 1961

1.2. Characterization of the Field

Optical metrology  essentially measurement of length

Industry:

Precision measuring technique



Demands

- Positioning accuracy of workpieces $< 20 \text{ nm}$
- Reproducibility of dimensional measurements $< 10 \text{ nm}$

Machine building

- Lengths to be measured $\leq 100 \text{ mm}$ (... some m) with $\pm 1 \text{ }\mu\text{m}$

($1 \text{ }\mu\text{m}$ = extension of a Fe-rod (1 m) for $\Delta T = 1 \text{ K}$)

1.2. Characterization of the Field

Characterization of measuring devices

- 1) Test piece/specimen/measuring object scanning/sensing
- 2) Measurement signal (material measure, standard, etalon)
- 3) Amplification of the signal
- 4) Indication of the measured value

If 1) or 2) or 3) is performed out optically

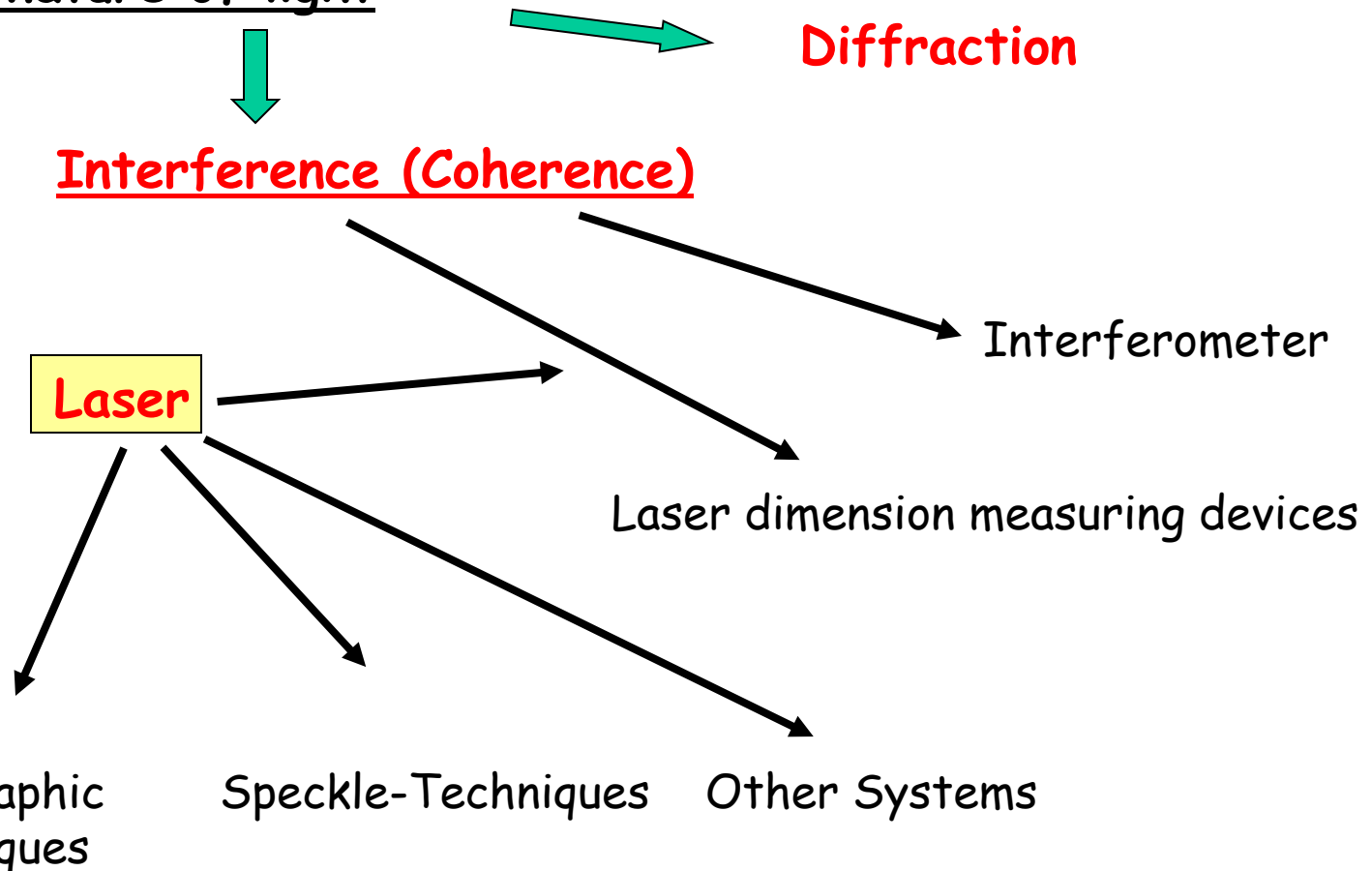


Optical measuring instrument

1.2. Characterization of the Field

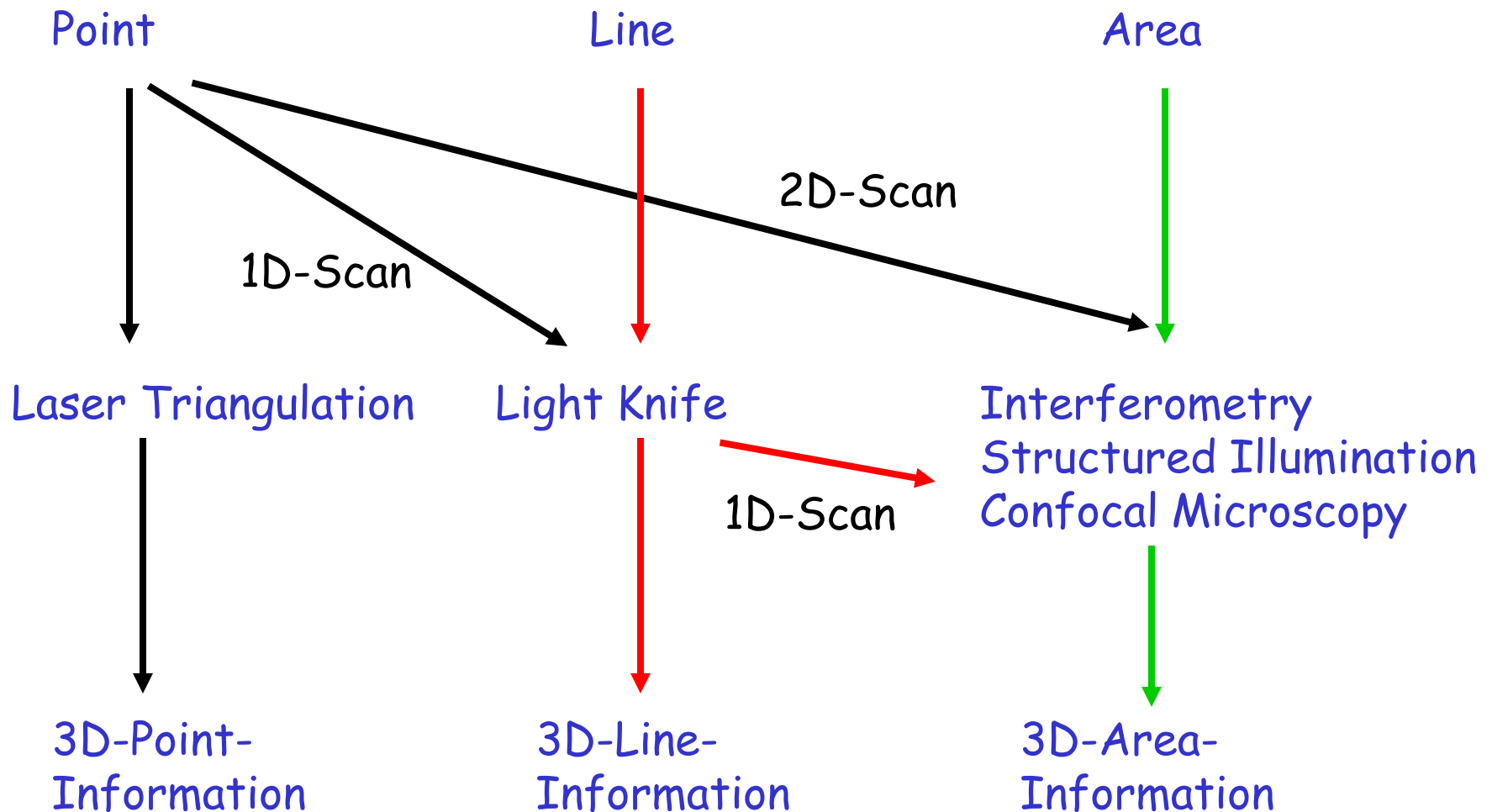
Methods

Wave nature of light



1.2. Characterization of the Field

Classification



1.2. Characterization of the Field



**Result of Measurement = Measured Value \pm Uncertainty
of Measurement**



1.2. Characterization of the Field

Measurement Terms

Accuracy: In situations where we believe that the **measured value is close to the true value**, we say that the measured value is accurate.

Precision: When **values** obtained by repeat measurements of a particular quantity **exhibit little variability**, we say that those values are **precise**.

Attention: Precision and accuracy are qualitative terms!



1.2. Characterization of the Field

Measurement Terms

- Repeatability: How capable a gage is of providing the same reading for a **single user** when measuring a specific sample.
- Reproducibility: Ability for **different users** to get the same reading when measuring a specific sample.
- Resolution: Smallest amount of input signal change the instrument can detect reliably.
- Sensitivity: Smallest signal the instrument can measure.



1.2. Characterization of the Field

Result of Measurement = Measured Value \pm Uncertainty of Measurement

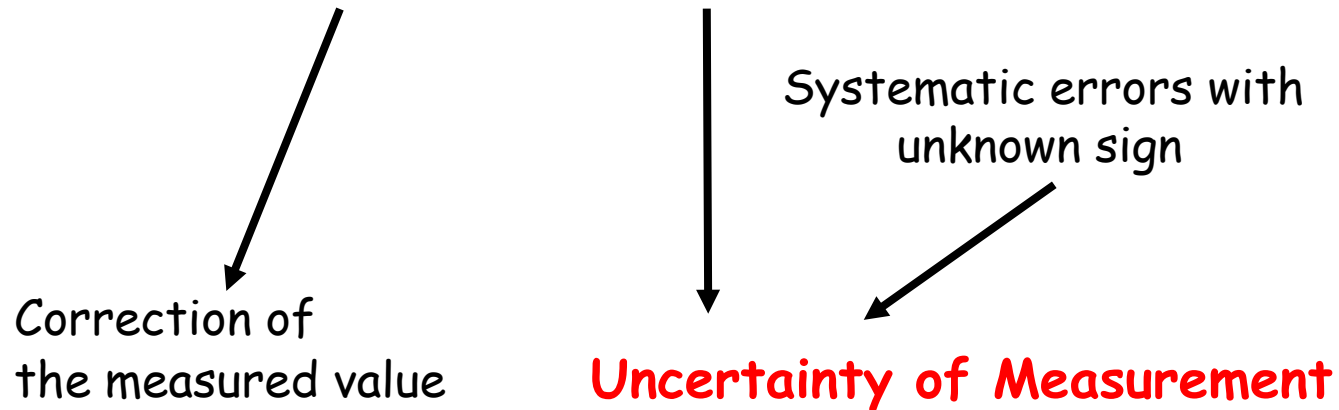
Errors (selection)

- Material measure (standard, etalon)
- Mechanical "failures" of the system
- Distortion of the Abbe comparator principle
- Environments
- Experimenter/observer

1.2. Characterization of the Field



Systematic and Random Errors





1.2. Characterization of the Field

Normal (Gaussian) distribution of measured values

Within interval $\pm \sigma$ are 68.27 % \forall measured values (statist. certainty: 68.27 %)

Within interval $\pm 2\sigma$ are 95.45 % \forall measured values (statist. certainty: 95.45 %)

Within interval $\pm 3\sigma$ are 99.73 % \forall measured values (statist. certainty: 99.73 %)

Denotation:

For a given statistical certainty the corresponding range is called $\pm c \cdot \sigma$ confidence interval (CI).

The true value lies within the confidence interval for a given statistical certainty if there are no systematic errors.

1.2. Characterization of the Field

Propagation of errors

Systematic Errors:

$$df = \frac{\partial f}{\partial x} dx + \frac{\partial f}{\partial y} dy + \frac{\partial f}{\partial z} dz$$

Statistical Errors:

$$u = \pm \sqrt{\left(\frac{\partial f}{\partial x}\right)^2 (dx)^2 + \left(\frac{\partial f}{\partial y}\right)^2 (dy)^2 + \left(\frac{\partial f}{\partial z}\right)^2 (dz)^2}$$



1.3. Definition of the Meter

Definition of the Meter

1791: French Academy of Sciences

1 m = one ten-millionth part of the quadrant of the earth's meridian

1875: Treaty of the Meter (Meter Convention)

General Conference on Weights and Measures (GCPM)

International Bureau of Weights and Measures (BIPM)

1889: International Prototype

("final" definition 1927 by 7th GCPM)

1.3. Definition of the Meter

Uncertainty of the Prototype

1. External conditions

$$\Delta T = \pm 0.001^\circ \quad \longrightarrow \quad \boxed{\Delta l/l = \pm 10^{-8}}$$

2. Measurement procedure

- Engraved lines
- Illumination, cross section, contamination

$$\longrightarrow \quad \boxed{\Delta l/l = \pm 2 \cdot 10^{-7}}$$

3. Instability



$$\text{Uncertainty} \left\{ \begin{array}{l} > \pm 10^{-7} \\ < \pm 10^{-6} \end{array} \right.$$

1.3. Definition of the Meter

Required Accuracy

Everyday life: $\Delta l/l = \pm 10^{-3}$ (commerce)

$\Delta l/l = \pm 10^{-6}$ (gauge block)

Physics: $\Delta l/l = \pm 10^{-7}$

Problems with the Prototype

- arbitrary unit
- unique unit
 - ➡ Hierarchy of secondary standards, prototypes
 - ➡ Propagation of errors

1.3. Definition of the Meter

Definition of the Meter based upon the Wavelength

1893: **Michelson: 1st measurement** with red Cd-line

1906: Benoit, Fabry, Perot: measurement repeated

1927: 7th GCPM

red Cd - Line = primary standard for spectroscopy

(dry air, 15 °C, 101.33 kPa, carbonic acid 0.03 volume percent)

Disadvantages

- 1) Wavelength in air
- 2) Cd - emission non-monochromatic
- 3) Michelson - Lamp
- 4) Bad reproducibility
- 5) Insensitive SEM's



1.3. Definition of the Meter

1960: 11th GCPM

Kr - wavelength = new standard

1m = 1,650,763.73 vacuum wavelength of the radiation of



($\lambda = 605.8 \text{ nm}$)

Advantages

- 1) Vacuum
- 2) No Hyperfine structure
- 3) No instruction for the generation of the radiation

Uncertainty

$$\Delta l/l = \pm 10^{-8} \dots \pm 4 \cdot 10^{-9}$$



1.3. Definition of the Meter

1983:

1 m = length of the path travelled by light in vacuum during a time interval of $1/299,792,458$ s

SI base units	relative uncertainty (realization)
s	10^{-14}
m	10^{-14}
kg	0
A	10^{-6}
K	10^{-6}
mol	10^{-5}
Cd	$5 \cdot 10^{-3}$

1.4. Some Basics

Coherence = Capability of Interference

→ Correlation of wave fields
(coherence function)

a) Spatial Coherence

Coherence = f (dimensions of the source of light)

→ Point source = spatially coherent

Measurement procedure: Young Interferometer

b) Temporal Coherence

Finite „wave train“

path difference too high → no interference

Measurement procedure: Michelson interferometer



1.4. Some Basics

Temporal Coherence

Source	$\Delta\lambda$ [nm]	$\Delta\nu$ [Hz]	Δl_c [m]
Hg (high-pressure) 546 nm	10	10^{13}	$3 \cdot 10^{-5}$
Hg (low-pressure) 546 nm	1	10^{12}	$3 \cdot 10^{-4}$
Ar-Laser 514 nm	$9 \cdot 10^{-3}$	10^{10}	$3 \cdot 10^{-2}$
He-Ne-Laser (multimode) 633 nm	$4 \cdot 10^{-3}$	$3 \cdot 10^9$	0,1
He-Ne-Laser (stabilized) 633 nm	$1.3 \cdot 10^{-10}$	100	$3 \cdot 10^6$
LED 631 nm	$3 \cdot 10$	$3 \cdot 10^{13}$	10^{-5}